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APPLICANT

Calvin T. Gabriel et al.

FILING DATE

03/28/2001

GROUP ART UNIT

1756. 1746

INFORMATION DISCLOSURE CITATION

JUL 30 2001

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS AUG 01 2001	SUB- CLASS	FILING DATE IF APPROPRIATE
		09/819,342		Shields et al			03/28/01
		09/819,344		Okoroanyanwu et al			03/28/01
		09/819,552		Gabriel et al			03/28/01
		09/819,692		Okoroanyanwu et al			03/28/01
		09/820,143		Okoroanyanwu et al			03/28/01
WS		6,107,172	08/22/00	Yang et al	438	585	
WS		6,103,457	08/15/00	Gabriel	430	318	
WS		5,965,461	10/12/99	Yang et al	438	717	
WS		5,003,178	03/26/91	Livesay	250	492.300	

FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

WS		Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov./Dec. 1993, pp. 2304-2308, American Vacuum Society
WS		Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society
WS		Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering
WS		Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)

EXAMINER

WS egan

DATE CONSIDERED

8/21/01

* EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include any copy of this form with next communication to applicant.